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10/13/01

U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10014387	12/11/2001	204	298.4	1753	CANTELMO

**APPLICANTS: Shi Xu; Tay Beng; Flynn David; Tan Hong; Fulton Michael;

**CONTINUING DATA VERIFIED:

This application is a CIP of 08/894,419 11/21/1997 ABN

** FOREIGN APPLICATIONS VERIFIED:

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PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no

35 USC 119 conditions met ☐ yes ☐ no

Verified and Acknowledged Examiners's initials

ATTORNEY DOCKET NO

GWS/18240CIP

TITLE : Filtered cathode arc source deposition apparatus

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs. Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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